

Nové možnosti rozvoje vzdělávání na Technické univerzitě v Liberci

Specifický cíl A2: Rozvoj v oblasti distanční výuky, online výuky a blended learning

NPO_TUL_MSMT-16598/2022



Smart oděvy







SOD

Smart oděvy

e-textilie - senzory



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NPO_TUL_MSMT-16598/2022

- Měření tlaku, teploty, vlhkosti
- Senzory plynů
 - výbušné metan, propan, butan, páry hořlavých látek,..
 - Produkty hoření oxidy dusíku, síry, uhlíku, produkty hoření plastů
 - Smog
 - Mění se elektrické, optické či jiné vlastnosti senzoru, to lze snímat a vyhodnotit
- Lze je integrovat do textilu



- Oděvy pro hasiče, polici, záchranáře, armádu, atd.
- Integrace do oděvu, uniformy
- Monitorování životních funkcí

- Monitorování životních funkcí
- EKG (např. vyšívané elektrody)
- Tepová frekvence
- Frekvence dýchání
- Tlak krve
- Teplota, vlhkost
- Poloha těla

An overview of the most common sensors used in smart clothing:

Breathing (respiration) - sensor for monitoring breathing frequency. It is based on changes in elasticity and conductivity of the material.





Puls

the sensor for monitoring pulse.

> Pressure

- the sensor for measuring pressure, max. Field size is 500 x 400 mm. The maximum pressure range is 7-350 kPa, the substrate material is - elastomer Lycra (Dupont).





Thermal field

sensor for measuring the **thermal field** using copper wire network.

Measurement consists in the use of constant current and recording the temperature change that is converted into an electrical resistance.



Textile electrode - multilayer knitted fabric that contains as an active layer, and a protective inactive.







Textrody - ECG T-shirt

It measures the cardiovascular system of the wearer, is used as a substitute for conventional gel electrodes. The use of electrolytic properties of sweat, direct contact with the skin (without the use of electrical stimulation gel).







www.MaterialsViews.com



Figure 3. Fiber transistors: (a) fiber organic field-effect transistors (OFETs), (b) wire electrochemical transistors (WECT). Reproduced with permission.^[78a] Copyright 2007, Nature Publishing Group.









PDMS-RET 31 mm 5 mm substrate 8 mm 56 mm 100 Probe feeding **E-fibers** antenna **Dual polarized textile antenna** 64 mm dielectric fabrics conductive patch Antenna Patch 49 Microstrip 1 Feedline Substrate (Dielectric) 47 mm Ground Plane 10-0 0 The fundamental composition 21 feed ground plane slot of a patch antenna All textile antenna Realization 1.5mm Slot **Circularly Polarized** 10cm textile antenna 10cm Loop reeding loading 1.5mm Slot 6cm 6cm Textile triband antenna

Figure 4. Fabric antennas based on the fundamental composition of a patch antenna: E-fiber antenna,^[87] textile triband antenna,^[89] dual polarized textile antennas,^[90] all textile antenna,^[85] and circularly polarized antenna.^[91] Reproduced with permission. Copyright, respectively, 2012, 2012, 2011, 2006, 2011, IEEE.



Figure 7. Fiber circuitry: (a) A binary tree multiplexer constructed from WECTs and their dynamic electrical characteristics, Reproduced with permission.^[52] Copyright 2007, Nature Publishing Group. (b) A woven inverter circuit and its dynamic electrical characteristics, Reproduced with permission.^[135] Copyright 2004, IEEE. (c) Fiber-based fabric-array memory device. Reproduced with permission.^[136] Copyright 2011, WILEY-VCH Verlag GmbH & Co. KGaA, Weinheim.



Figure 8. Fiber-based sensors: (a) Fabric bio-potential electrode and its SEM photo, Reproduced with permission.^[144] Copyright 2010, IEEE. (b) Pulsedriven fiber nanogenerator by ZnO thin films grown around a carbon fiber as a strain sensor, Reproduced with permission.^[6a] Copyright 2011, WILEY-VCHVerlag GmbH & Co. KGaA, Weinheim. (c)Vibration sensor arrays of piezoelectric fibers in gloves for detection and suppression of Parkinson's tremor in the hand, Reproduced with permission.^[145] Copyright 2009, Textile Bioengineering and Informatics Society. (d) Carbon loaded elastomer sensorized garment for kinesthetic monitoring, Reproduced with permission.^[146] Copyright 2011, Cambridge University Press. (e) Strain-gauge sensor based on the reversible interlocking of Pt-coated polymer nanofibres, Reproduced with permission.^[140] Copyright 2011, Nature Publishing Group. (f) Carbon nanotube strain sensor for human motion detection, Reproduced with permission.^[20c] Copyright 2011, Nature Publishing Group. (g)Woven electronic fibers with sensing and display functions, Reproduced with permission.^[5b] Copyright 2010, WILEY-VCH Verlag GmbH & Co. KGaA, Weinheim. (h) In-shoe plantar pressure monitoring in daily activities by fabric pressure sensors. Reproduced with permission.^[140] Copyright 2010, IEEE.

Zdroje napájení?



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Dá se energie získat?



Figure 10. Available power for everyday bodily activities of human being.^[153]

Tlak

Sensor tlaku



Sensors 2018, 18(4), 1190; https://doi.org/10.3390/s18041190

Sensor tlaku





Smart-surface: Large scale textile pressure sensors arrays for activity recognition JingyuanChengMathiasSundholmBoZhouMarcoHirschPaulLukowicz Smart-surface: Large scale textile pressure sensors arrays for activity recognition - ScienceDirect





Monitorování tlakového pole



J.J. Liu et al. / Pervasive and Mobile Computing 10 (2014) 34–50

Fig. 1. Human body pressure image samples.





<u>Highly elastic capacitive pressure sensor based on smart textiles</u> for full-range human motion monitoring - ScienceDirect



The sock and anklet work together to provide runners with valuable data.

© Sensoria

Each smart sock is infused with three thin, soft textile pressure sensors. © Sensoria





https://doi.org/10.1002/smll.201901558

Silk Composite Electronic Textile Sensor for High Space Precision 2D Combo Temperature-Pressure Sensing - Wu - 2019 - Small - Wiley Online Library Schema of the strategy of fabrication of silk fibers-wrapped combo temperature-pressure sensors:

- a) Coiling supporting yarns by silkworm silk fibers;
- b) coating the silk fibers coiled yarns with temperature or pressure sensing materials (the mixture of CNT and a ionic liquid for temperature sensing; and Ag NWs for pressure sensing);
- c) coating the protection or dielectric layers on the functional yarns/fibrous sensors;
- d) weaving the fibrous sensors into a combo two-layer multimode sensors textile.



In HK, Fashion Can Be Intelligent | Fashion in HK (wordpress.com)





a) Left: Schematic illustration of polymerization of PEDOT on a polyester ٠ (PS) fiber. Middle: optical images of linear- and zigzag-type textile strain sensor-embedded fabrics. Right: optical microscope images of PEDOT/PS textile strain sensors showing the immobilized PEDOT/PS fibers after interlocking with the PS fibers. Reprinted with permission from Ref. 78 Copyright 2017 American Chemical Society. b) Schematic structure and SEM image of (Top left) the elastic thread surface, (Top middle) the P(VDF-TrFE) layer around the thread fiber surface after electrospinning, and (Top right) the Ag nanowires layer after five dip-coating times. Bottom left: SEM image of the cross section of AgNW coated core-spun yarn. Bottom middle: elative resistance variation in P(VDF-TrFE)-based fibers when being stretched up to 100% strain. Bottom right: resistance variation under gradually ascending step strain from 0% to 15% strain. The inset shows the cyclic response curve at consecutive input step strain of 0.5%. Reprinted with permission from Ref. <u>68</u> Copyright 2016 John Wiley & Sons, Inc. c) Left: schematics illustration of the self-developed fabrication process of the PU/cotton/CNT yarn. Middle: schematics illustration showing the stretchability and the morphological comparison before and after stretching. Right: relative change in resistance of the eighth and 12th immersed yarns vs strain (%) (relative change in resistance defined as: $\Delta R/R_0$). Reprinted with permission from Ref.84 Copyright 2016 American Chemical Society.



a) Left: aluminum fiber; Right top: twisted metal wire; Right middle: • metal filaments yarn; Right bottom: metal-coated yarn. b) Top: SEM of directly spun CNT yarns from the as-grown CNT array. Middle: low magnification SEM of an as-spun yarn. Bottom: low magnification SEM of a yarn end coated with AI. Reprinted with permission from Ref.<u>90</u> Copyright 2010 IOP Publishing Ltd. c) Left: illustration of the fabrication process. The dry-spun CNT fibers attach directly to the elastic Ecoflex substrate. Middle: relative change in resistance versus strain for unsupported CNT fibers (black), CNT fibers on an unstrained Ecoflex substrate (red), and CNT fibers on an Ecoflex substrate prestrained by 100% (blue); the strain ranged from 0% to 450% strain (inset). Right: relative change in resistance versus strain for 10 (black), 1 000 (red), 1 000 (blue), and 10 000 cycles (green) for increases in the strain from 0% to 300%. Reprinted with permission from Ref.<u>93</u> Copyright 2015 American Chemical Society.


a) Left: schematic diagram showing the process to prepare GO fibers by ٠ wet-spinning methods and an image showing the continuous GO fibers wound around a ceramic reel; Right: photograph of the process to twist graphene fibers to yarns, and SEM images of the twisted yarn at different magnitudes. Reprinted with permission from Ref. 96 Copyright 2013, Wiley-VCH. b) Left: 4-m-long GO fiber wound on a Teflon drum (diameter, 2 cm); Right: SEM image of the fiber, and the surface winkled morphology of the tighten knot of graphene fiber, and A mat of graphene fibers (horizontal) woven together with cotton threads (vertical). Reprinted with permission from Ref.<u>95</u> Copyright 2011, Nature Publishing Group. c) Photograph and SEM images of graphene microtubings obtained by a confined hydrothermal technique. Reprinted with permission from Ref. 98 Copyright 2012, the American Chemical Society. d) Graphene fibers prepared by CVD combined with PVA for strain sensors. Reprinted with permission from Ref.<u>99</u> Copyright 2015, American Chemical Society.



a) Left: schematic illustration of the coaxial spinning process for the • highly stretchable fibers. Right: resistance change ($\Delta R/R_0$) as a function of the applied strain with different CNT contents, that is, 2 and 3 wt%. Reprinted with permission from Ref. 103 Copyright 2018 American Chemical Society. b) Left: schematic illustration of conducting elastomeric fibers based on composite of polyurethane (PU) and PEDOT:PSS produced by wet-spinning method. Middle: conductivity of PU/PEDOT:PSS fibers at different PEDOT:PSS contents (• PU 50 mg mL⁻¹, \blacksquare PU 40 mg mL⁻¹, and \blacktriangle PU 30 mg mL⁻¹). The curve indicates the best fit obtained using percolation theory. Right: resistance change by strain for PU/PEDOT:PSS fiber with 13.0 wt% PEDOT:PSS (No.6) in a cyclic electromechanical test at 50% and 100% strains for 10 cycles (inset shows the electromechanical tensile test for the same fiber). Reprinted with permission from Ref. 109 Copyright 2014 John Wiley & Sons, Inc. c) Left: schematic illustration of the fabrication process for the highly stretchable conductive fiber. Middle: cross-sectional SEM image and EDS mapping images of Ag, and C obtained from the 0.56 wt% AgNW-AgNP embedded composite fiber. Scale bar: 100 µm. Right: the normalized resistance changes varying the applied strains at 0%, 20%, 40%, 60%, 80%, and 100%. Reprinted with permission from Ref. <u>110</u> Copyright 2015 John Wiley & Sons, Inc.



a) Left: schematic illustration showing the fabrication process of a ٠ sheath-core fiber; Middle: the hierarchical buckling shown in the SEM image; Right: sheath-core CNT fibers for strain sensors. Reprinted with permission from Ref.54 Copyright 2015, the American Association for the Advancement of Science. b) Left: schematic illustration showing the fabrication process of a self-powered strain sensor made of an elastic fiber and two cotton threads coated with CNTs and PTFE/CNTs, respectively; Middle: output current-time curves; Right: the peak value of the output currents and integral transferred charges of an AFSS varied with stimulated strains of 5%, 10%, 15%, 20%, and 25%. Reprinted with permission from Ref. <u>126</u> Copyright 2015, Wiley-VCH. c) Left: schematic illustration of a twist-inserted rectangular sandwich fiber, which comprises an Ecoflex rubber core and two symmetric, buckled CNT electrodes; Middle: photographs of 20 cm long sandwich fiber woven into a commercial glove and magnified images thereof before and after application of 60% tensile strain (scale bar: 8 mm); Right: photograph image showing an 8 cm long coiled nylon torsional artificial muscle and attached sandwich sensor (scale bar = 2 cm). Inset images show the magnified muscle and sensor when heated by a heat gun. Reprinted with permission from Ref. <u>55</u> Copyright 2016, the American Chemical Society.



a) Top: illustration showing the hierarchical structures and the fabrication ٠ of CSF strain sensors. A plain weave structure is used as an example; Bottom: enlarged optical images of a carbonized plain weave silk fabric, and a photograph of the pristine and stretched CSF strain sensor, showing its ultraelasticity, and relative change in resistance of the strain sensor versus the applied strain in the y-direction (strain rate 30% min⁻¹). Reprinted with permission from Ref. <u>132</u> Copyright 2016, Wiley-VCH. b) Left: schematic illustrations of fabrication procedure of a human motion sensor based on graphene woven fabrics (GWFs)-PDMS-medical tape film; Right: a magnification of the optical microscope image and the inset is the relative change in resistance between 0% and 0.2% strain. Reprinted with permission from Ref.<u>133</u> Copyright 2014, Wiley-VCH. c) PEDOT-printed woven cotton fabric and resistance of PEDOT-PSS sensor with 25 repeated cycles of strain to 5% and relaxation. Reprinted with permission from Ref. <u>134</u> Copyright 2008 Taylor and Francis.



a) Tubular steel (Top left) and carbon (Top middle) knitted fabric; Top right: single warp steel (left) and carbon (right) knitted fabric, resistance-strain relationships of samples: tubular carbon knitted fabric (Bottom left), single warp steel (Bottom middle) and carbon (Bottom right) knitted fabric. Reprinted with permission from Ref. 139 Copyright 2005 Elsevier B.V. b) Technical face of knitted sample shows conductive loops in the structure and relative change in resistance-strain graphs. Reprinted with permission from Ref.<u>141</u> Copyright 2013 MDPI. c) Single-layer knitted piezoresistive fabrics (KPF) sample attached to a Lycra[®] substrate. Reprinted with permission from Ref.<u>142</u> Copyright 2017 Springer International Publishing AG. d) Optical images of the graphene non-woven fabric (GNWF) (reduced GO (rGO) loading 2.3%) and normalized resistance change during a cyclic bending test. Reprinted with permission from Ref.<u>143</u> Copyright 2016 the Royal Society of Chemistry.



a) Top: schematic illustration of the fabrication process and the • characterization of the graphene-based fiber; Bottom left: resistance variation under gradually diminishing step strain from 5% to 0.2% strain. The inset shows the response signal at 20 consecutive input step strain of 0.2%. Bottom middle: photograph of the wearable sensor. Bottom right: response signal of wearable sensor in monitoring finger bending. Inset: photographs of finger bending to the corresponding positions. Reprinted with permission from Ref. <u>100</u> Copyright 2015 Wiley-VCH. b) Left: fabrication of sheath-core structured graphite/silk strain sensors through a dry-Meyer-rod-coating process; Middle: relative change in resistance versus strain of a graphite/silk fiber (GSF) strain sensor when being stretched until broken; Right: response of the wearable sensor to stepwise bending of an index finger (insets show photographs of a strain sensor attached along a finger, using adhesive tape). Reprinted with permission from Ref.<u>86</u> Copyright 2016, the American Chemical Society. c) Kinesthetic and kinetic glove pair and functional hand grips to be classified. Reprinted with permission from Ref. 144 Copyright 2016 Lorussi, Carbonaro, De Rossi, Paradiso, Veltink, and Tognetti





a) Top: illustration showing the structure of the pristine cotton fabric and the fabrication process of the carbonized plain weave cotton fabric (CPCF) strain sensor; Bottom: relative resistance change as a function of tensile strain, and monitoring of human motion using the CPCF strain sensors and the response to motions of knee joint, the insert is the photograph of the strain sensor. Reprinted with permission from Ref. 135 Copyright 2016, Wiley-VCH. b) Top: a wrist guard and a stocking. Middle: the corresponding signals of the bending and rotation of a wrist; Bottom: the corresponding signals of flexing/extending, marching, jogging, jumping, and squatting-jumping of a knee joint. Reprinted with permission from Ref. 132 Copyright 2016, Wiley-VCH. c) Single-layer strain sensor is positioned in the scapular area in order to detect scapular elevations and abductions, and IMU (bottom), strain sensor (middle), and EMG (top) outputs during reaching activity. Left plot data acquired during a correct reaching movement. Right plot data derived from a compensatory movement are plotted. Reprinted with permission from Ref. 144 Copyright 2016 Lorussi, Carbonaro, De Rossi, Paradiso, Veltink, and Tognetti. d) Top left: response of the wearable sensor to cyclic motion of a wrist (insets show photographs of a strain sensor attached on a wrist) and integrated rosette-shaped GSF strain senor for multidirectional motion detection. Top middle: illustration of the configuration of the strain sensor composed of three individual fiber strain sensors (GSF-A, GSF-B, and GSF-C); Top right: photographs of the strain sensor attached on a wrist. Bottom: responsive signals of GSF-A (left), GSF-B (middle), and GSF-C (right) during cyclic bending – unbending motion of the wrist. Reprinted with permission from Ref.86 Copyright 2016, the American Chemical Society. e) Left: wearable sensor attached to the knee, marked in the red box, and responsive curves of wearable sensor on the knee under motions of flexing/extending, walking, jogging, jumping, and squatting-jumping; Right: wearable sensor attached to the wrist, marked in the red box, and responsive curves of wearable sensor on the wrist before wearing (no load), and under normal/exercise conditions. Reprinted with permission from Ref. 100 Copyright 2015 Wiley-VCH.

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a) Photograph images of GWFs-PDMS-tape at various positions of, and • relative change in resistance in muscle motions of expression changes. Reprinted with permission from Ref.<u>133</u> Copyright 2014, Wiley-VCH. b) Top left: wearable sensor attached to the throat, marked in the red box, and responsive curves when wearer spoke "Hi," "Hello," "Sensor," and "Graphene"; Top right: wearable sensor attached to the wrist, marked in the red box, and responsive curves of wearable sensor on the wrist before wearing (no load), and under normal/exercise conditions; Bottom left: wearable sensor attached to the chest; Bottom middle: responsive curves of wearable sensor on the chest before wearing, in relaxation, and after exercise; Bottom right: responsive curves of wearable sensor on the chest. The wearer simulates deep sleep (keeping still) and light sleep (turning over and trembling frequently). Reprinted with permission from Ref. <u>100</u> Copyright 2015 Wiley-VCH. c) Signals showing the tiny muscle movement caused by blinking. Insets: photographs of eye-opening, eyeclosing, and photograph showing a sensor attached on an earphone, and signals of the sensor corresponding to a warble audio. Inset: the sound wave profile. Reprinted with permission from Ref. <u>132</u> Copyright 2016, Wiley-VCH.

Taktilní sensory



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The flexible tactile sensing glove is manufactured from several layers of conductive and piezo-resistive fabrics.

 <u>The flexible tactile sensing glove is manufactured from several</u> layers... | Download Scientific Diagram (researchgate.net)







-



DoFs	Description	
TA	Thumb Abduction	
TR	Thumb Rotation	
ΤM	M Thumb Metacarpal	
ΤI	Thumb Interphalangeal	
IA	Index Abduction	
IM	Index Metacarpal	
IP	Index Proximal	
ID	Index Distal	
MM	Middle Metacarpal	
MP	Middle Proximal	
MD	Middle Distal	
RA	Ring Abduction	
RM	Ring Metacarpal	
RP	RP Ring Proximal	
RD	Ring Distal	
LA	Little Abduction	
LM	Little Metacarpal	
LP	Little Proximal	
LD	Little Distal	

		MM RP LM
Joint	Sensor Lenght (mm)	LA
TA	82	TA
MM	72	
RP	62	
LM	60	
LA	74	VA THE





 Piezoresistive Tactile Sensor Arrays: (a) illustration of resistance changes in conductive rubber [47],(b) nano-scale image of conductive rubber [48], (c) structure of piezoresistive tactile array [49], (d) piezoresistive fabric tactile sensor [50], (e) schematic of electrode layer of the 3D-shaped tactile sensor [34], (f) tactile image of a piezo-resistive pressure sensor array [35].



 Capacitive Tactile Sensing Technology: (a) capacitance of a parallel plate capacitor depends on distance between plates d and area of the plates A (q is the stored charge) [45]; (b) two conductive plates are separated by an elastic dielectric-as force is applied, the distance between the plates reduces, changing the capacitance [9]; (c) mesh of triangle shape capacitive sensors for the palm of the iCub humanoid robot [44].



 Piezoelectric Tactile Sensing: (a) the piezoelectric effectan applied force causes rearrangement of positive Si and negative O 2 particles leading to an increase of potential [45]; (b) a tactile sensing array based on the piezoelectric effect with electrodes on the bottom layer, piezolectric material in the middle and rubber on the top [24], (c) schematic model of a piezoelectric sensing tactel [71]







(d)

(f)

• Optical Tactile Sensors: (a) an optical tactile transducer based on the principle of frustrated total internal reflection [45], (b) a structure of optical threeaxis tactile sensor: a displacement of a sensing element fixed on flexible finger surface causes changes in light propagation in opto-fibers [37], (c) fingers with the sensitive optical sensors manipulating a light paper box [37], (d) photo of an optical 3 x 3 tactile array with magnetic field compatibility [77], (e) "GelSight" optical sensor consisting of a piece of clear elastomer coated with a reflective membrane senses the shape of the cookie surface [79], (f) finger configurations of the "GelSight" sensor [79].



 Sensors based on barometric measurements: (a) the structure of a tactile sensing cell with a barometer and silicon rubber (b), the TakkStrip tactile array of these cells [87], (c) custom shaped array of the pressure sensing barometers of the iHY hand [42], (d) micro-vibration sensing system based on a fluid pressure sensor of the BioTac tactile sensor [83].





 Multimodal Tactile Sensors: (a) schematic of the biomimetic BioTac tactile sensor with 19 electrodes, fluid pressure sensor and thermometer [84], (b) photo of the multimodal BioTac tactile sensor, (c) combined tactile-proximity sensor that can measure both the distance to an object and the contact pressure [90], (d) drawing of a multi-modal tactile sensing module consisting of optical and piezoresistive sensors [76].







 Three-fingered robot hands with tactile sensors: (a) a finger with tactile sensor of the 3-fingered high-speed robot hand [101], (b) assembly of tactile sensing arrays with a robot finger of the Universal robot hand with 3 movable and 2 immovable fingers [35], (c) schematic illustration of a finger of the iHY robot hand with embedded array of pressure sensors based on digital barometers placed inside the soft paddings of the fingers [42]; (d) schematic illustration of the integration of a multimodal sensing system with a three-fingered robot hand [76]






(a) P1 Grab

(b) P7 Stroke





- a) Structure model and sensing mechanism of the tactile sensor.
- b) Model of the knitted textile.
- c) Structure and resistance model of the knitted textile and simulation of surface potential distribution.





a) Photos of the sensor with different pore diameters of the polyurethane foam from ≈0.5 to ≈2 mm. b) Resistance changes as a function of the applied force.
c) Compiled detectable threshold force extracted from panel (b). d) Resistance changes as a function of the applied force. e) Compiled detectable threshold force extracted from extracted from panel (d) with 2 mm pore diameter. f) Cycle tests as 80 kPa applied force.





• DOI 10.1021/acs.nanolett.9b00922



Schematics of TRACE sensor and applications in health monitoring and robotics tactile perception.



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 Schematics of TRACE sensor and applications in health monitoring and robotics tactile perception. (A)Illustration of TRACE piezoresistive tactile sensing elements with 3D and regularly cracked bilayer micropyramids made of metal film and elastomer microstructure. (B) Scanning electron microscope (SEM) image of Pt-coated micropyramid array with controlled annular cracks. (C) Demonstration of local PWV measurement on a single-patch healthcare wearable by assembling TRACE on multichannel electrodes. (D) Illustration of TRACE sensor matrix on a prosthetic hand with a flexible sensor array. (E) Schematic of one-touch surface texture classifications.



Mechanism of SIP method for regular annular cracks. (A) Comparison of • random and controllable annular cracks of Pt film on micropyramid (*Top* view). The pristine Pt-film coating on micropyramid elastomer leads to the onset crack on the tips due to intensive stress concentration, propagating into uncontrollable random cracks with the increase of pressure. The proposed SIP method can generate regular and annular morphology cracks by rearranging stress distribution on bilayer micropyramid. (B) The optimized electromechanical property of the SIP method with annular cracks compared to random cracks. The annular cracks-induced gradual trend of piezoresistance is more suitable for a tactile sensor for a wide range of pressure, in comparison with sharp drops of resistance based on random cracks. (C) Schematic of SIP method for generating annular cracks of Pt film on micropyramid. (D) Theoretical model of SIP method for the design of stiff Pt film/PDMS bilayer micropyramid structure when applied compression force, where α , *h*, and *h*_c are the sidewall angle of the pyramid, indentation depth, and the depth of the contact region, respectively. (E) FE simulation of stressfield distribution of bilayer microstructure by SIP method. The maximum stress occurs in annular fashion in a one-quarter model of bilayer structure (*Left*), and the stress distribution of Pt film on the surface (*Right*).



Piezoresistive response of TRACE sensor. (A) The schematic • model of the conductive pathways of TRACE sensor under compressing loads. (*B*) The pressure-induced electrical performance of TRACE sensor, compared with the PEDOT:PSScoated micropyramid sensor. (C) Benchmark of TRACE sensor with both sensitivity and hysteresis being considered. We used S_p/DH_e as an indicator to simultaneously evaluate sensitivity and hysteresis of resistive-type sensors, where S_p represents the peak sensitivity, and DH_e is the degree of hysteresis, respectively. The smaller DH_{e} (or namely, larger $1/DH_{e}$) means a lower hysteresis observed for the piezoresistive sensor, indicating more accurate and repeatable sensing performance of TRACE sensor. Yellow region: low hysteresis; orange region: high sensitivity. (D) The ability of TRACE sensor to detect a small pressure of a *floribunda* petal under the preload of 7 kPa, where $_{\sigma_1}$ is the conductance of the preload pressure of 7 kPa, respectively, where the black scale bar is 10 mm. (E) The output voltage of TRACE sensor under different frequencies when applied pressure. (F) Cyclic testing of TRACE sensor: time-resolved performance of successive 10 cycles (Top) and maximum conductivity change over 10,000 cycles (*Bottom*).

Životní funkce



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Měření tepu



Superficial pulse measurement and pulse tracing. (A) The illustration of superficial pulse measurement located on the human neck and wrist. The zoom-in images show the photographs of the pulse measurement on a volunteer. (B)The graphs show results of the simultaneous pulse measurement at the carotid artery and radial artery, and (C) a zoom-in image showing the measurement result of one radial pulse. The specific peak and wave information are indicated. (D) The optical image of flexible electrodes with multiple channels. (*E*) The photograph showing localized pulse tracing by integrating TRACE sensor with multichannel electrodes. (F and G) The graphs showing the results of localized pulse measurement at the radial artery and pulse tracing.

High-Density Pressure Mapping and Tactile Detection



 High-density pressure distribution mapping on a robotic hand. (A) Images of conformable electrodes of TRACE-SA/FA sensor matrix attached to the index fingertip of a robot hand. (B) Design of electrodes (10×10) of sensor matrix, and laser-cut N, U, and S letters were touching TRACE-SA sensor matrix. (*C-H*) The pressure distribution map of TRACE-SA sensor matrix touching N, U, and S letters at different rotate angles

Robotic fingertip embodiment of TRACE sensor for pulse sensing

- Electromechanical sensor transforms mechanical stimulus into electrical signals. The main electromechanical sensors we focus on are strain and pressure sensors, which correspond to two main mechanical stimuli.
- According to their mechanisms, resistive and capacitive sensor attracts more attention due to their simple structures, mechanisms, preparation method, and low cost. Various kinds of nanomaterials have been developed to fabricate them, including carbon nanomaterials, metallic, and conductive polymers. They have great potentials for health monitoring, human motion monitoring, speech recognition, and related human-machine interface applications.



What is the functional principle of a resistive pressure transmitter? - WIKA blog



What are electromechanical sensors? - Quora



What are electromechanical sensors? - Quora

Wearable pressure sensor

 A wearable pressure sensor converts pressure into an electrical signal. The pressure sensor can be fabricated with interlocked structures, percolative networks of nanomaterials, microfabricated structures (e.g., micro pyramids, micropillars), porous structures (e.g., sponges, foams, porous rubbers), and so forth. The image2 presents a pressure sensor fabricated with an interlocked micro dome array. The contact between the micro dome increases when pressure is applied, thus decreasing the tunneling resistance.



Tailoring force sensitivity and selectivity by microstructure engineering of multidirectional electronic skins | <u>NPG Asia Materials (nature.com</u>)

- a Schematic illustration of the main structure of the e-skins with interlocked microstructures.
- **b** Schematic showing the bulk film resistance $(R_{\rm F})$ and the contact resistance $(R_{\rm C})$ between the two neighboring microstructured films.
- c Pressure-sensing mechanism of piezoresistive e-skins having interlocked microstructures.
- **d** Schematic illustration of conductive composites with different microstructured arrays.
- e Top and tilted (inset) SEM images of the microstructured composites with different surface morphologies (microdome, micropyramid, and micropillar)



Tailoring force sensitivity and selectivity by microstructure engineering of multidirectional electronic skins | <u>NPG Asia Materials (nature.com)</u>



Tailoring force sensitivity and selectivity by microstructure engineering of multidirectional electronic skins | NPG Asia Materials (nature.com)

- a Schematic illustration of the pressure-sensing principle of single microstructured e-skins with different surface morphologies.
- b Relative current changes in response to normal pressure.
- c Finite-element analysis (FEA) of localized stress distributions in response to pressure for different surface microstructure arrays (top layer: ITO, bottom layer: MWNT/PDMS composite).
- d Calculated relative contact-area changes in response to normal pressure



<u>Tailoring force sensitivity and selectivity by microstructure engineering of multidirectional electronic skins</u> | <u>NPG Asia Materials (nature.com)</u>



Tailoring force sensitivity and selectivity by microstructure engineering of multidirectional electronic skins | NPG Asia Materials (nature.com)



Tailoring force sensitivity and selectivity by microstructure engineering of multidirectional electronic skins | NPG Asia Materials (nature.com)

- Pressure sensors are categorized into
 - resistive,
 - Capacitive
 - piezoelectric types
- based on the pressure transduction mechanism
Picture and schematic diagrams of the pressure transduction mechanism.

- (a) Resistive type.
- (b) Capacitive type.
- (c) Piezoelectric type.



Applied Sciences | Free Full-Text | Recent Progress in Pressure Sensors for Wearable Electronics: From Design to Applications | HTML (mdpi.com), Copyright (2018), American Chemical Society.

Schematic of electrospinning technique and SEM images of electrospun NFs.

- (a) Electrospun PVDF-TrFE NFs at different solution concentrations of 14, 18, and 22 *w/v*% from the top to bottom of images.
- (b) Electrospun NFs of PVDF and PVP.
- (c) Schematic diagram of core-shell electrospinning technique and SEM



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Nanohair



Fabrication of slanted nanohairs with UV-curable PUA resin. (A)... | Download Scientific Diagram (researchgate.net)

Možnosti využití v biomechanice



Teplota, teplo



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Tepelný tok



Figure 2.6 A textile-based heat flux sensor comprising a thermoelectric wire woven into a textile substrate.

Jak vyrobit?





https://youtu.be/eXAlntc2y4s



https://youtu.be/oNCTTPauwmc



https://youtu.be/JDuBuy0HntA



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Konec



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